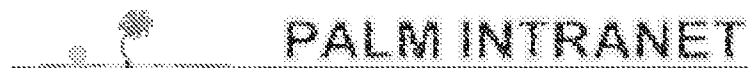


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Inventor Name Search Result

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Last Name = URA

First Name = MASAFUMI

Application#	Patent#	Status	Date Filed	Title	Inventor Name
09099872	5911826	150	06/19/1998	METHOD FOR PULLING CRYSTAL	URA, MASAFUMI
10588750	Not Issued	71	08/07/2006	Method for manufacturing single crystal semiconductor	URA, MASAFUMI
10948338	Not Issued	61	09/24/2004	Processing device, electrode, electrode plate, and processing method	URAKAWA, MASAFUMI
11392949	Not Issued	30	03/30/2006	Reduced contaminant gas injection system and method of using	URAKAWA, MASAFUMI
11518890	Not Issued	61	09/12/2006	Method and system for dry etching a hafnium containing material	URAKAWA, MASAFUMI
11956667	Not Issued	20	12/14/2007	Method and system for reducing line edge roughness during pattern etching	URAKAWA, MASAFUMI
11956676	Not Issued	19	01/01/0001	Silicon carbide focus ring for plasma etching system	URAKAWA, MASAFUMI
07802663	5152842	150	12/05/1991	REACTOR FOR EPITAXIAL GROWTH	URATA, MASAFUMI

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